

INFORMATION DISCLOSURE CITATION

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Applicants Yukiteru MATSUI et al.	
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U.S. PATENT DOCUMENTS						
Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
DVN	6,364,744 B1/	04/02/02	MERCHANT et al.			

FOREIGN PATENT DOCUMENTS						
	Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
DVN	2001-308041/	11/02/01	JAPAN			ABSTRACT

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
DVN	MATSUI, Y. et al., "Chemical Mechanical Polishing Slurry Containing Abrasive Particles Exhibiting Photocatalytic Function", Application Serial No. 10/201,488, filed on July 24, 2002. /

Examiner <i>Sung van Nguyen</i>	Date Considered 7-23-2004
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